

Expedited procedure  
Under 37 CFR 1.116



1204.41259X00

AF/8  
OC  
DFW

**IN THE UNITED STATES PATENT AND TRADEMARK OFFICE**

Applicants: T. UCHIDA, et al.  
Serial No. 10/069,404  
Filed: MAY 6, 2002  
For: POLISHING MEDIUM FOR CHEMICAL-MECHANICAL  
POLISHING, AND POLISHING METHOD  
Group AU: 1765  
Examiner: Lynette T. Umez Eronini  
Confirm. No: 3597

**AMENDMENT AFTER FINAL REJECTION**

**Mail Stop: AF – FEE**

Commissioner for Patents  
P.O. Box 1450  
Alexandria, VA 22313-1450

June 27, 2006

Sir:

In response to the Office Action mailed March 27, 2006, please amend the  
above-identified application as listed in the following, and as set forth on the  
following pages:

AMENDMENTS TO THE CLAIMS; and

REMARKS are included following the amendments.